

at a rate equal to the cash deposit of (or bond for) estimated antidumping or countervailing duties required on those entries at the time of entry, or withdrawal from warehouse, for consumption and to continue to collect the cash deposit previously ordered.

This notice is not required by statute but is published as a service to the international trading community.

Dated: June 14, 2000.

**Holly A. Kuga,**

*Acting Deputy Assistant Secretary, Group II, for Import Administration.*

[FR Doc. 00-15523 Filed 6-19-00; 8:45 am]

**BILLING CODE 3510-DS-P**

## DEPARTMENT OF COMMERCE

### International Trade Administration

#### **Allegheny-Singer Research Institute; Notice of Decision on Application for Duty-Free Entry of Scientific Instrument**

This decision is made pursuant to section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5:00 p.m. in Room 4211, U.S. Department of Commerce, 14th and Constitution Avenue, NW., Washington, DC.

*Docket Number:* 00-013. Applicant: Allegheny-Singer Research Institute, Pittsburgh, PA 15212-4772. Instrument: Robot and Microplate Manipulator, Model Q-Bot. Manufacturer: Genetix Limited, United Kingdom. Intended Use: See notice at 65 FR 26583, May 8, 2000.

*Comments:* None received. Decision: Approved. No instrument of equivalent scientific value to the foreign instrument, for such purposes as it is intended to be used, is being manufactured in the United States. Reasons: The foreign instrument provides a unique multi-tasking robotic system for the production, gridding and regridding of DNA arrays with: (1) A pneumatic picking head for sampling 3500 colonies per hour, (2) ability to create high density arrays on nylon filters, (3) replication of plates (96 or 384 wells) for distributing clones and (4) picking of both colonies or plaques. The National Institutes of Health advised in its memorandum of May 5, 2000 that (1) these capabilities are pertinent to the applicant's intended purpose and (2) it knows of no domestic instrument or apparatus of equivalent scientific value to the foreign instrument for the applicant's intended use.

We know of no other instrument or apparatus of equivalent scientific value to the foreign instrument which is being manufactured in the United States.

**Frank W. Creel,**

*Director, Statutory Import Programs Staff.*

[FR Doc. 00-15525 Filed 6-19-00; 8:45 am]

**BILLING CODE 3510-DS-P**

## DEPARTMENT OF COMMERCE

### International Trade Administration

#### **University of Michigan; Notice of Decision on Application for Duty-Free Entry of Scientific Instrument**

This decision is made pursuant to section 6(c) of the Educational, Scientific, and Cultural Materials Importation Act of 1966 (Pub. L. 89-651, 80 Stat. 897; 15 CFR part 301). Related records can be viewed between 8:30 a.m. and 5:00 p.m. in Room 4211, U.S. Department of Commerce, 14th and Constitution Avenue, NW., Washington, DC.

*Docket Number:* 00-011. Applicant: University of Michigan, Ann Arbor, MI 48109-1055. Instrument: Electron Beam Evaporator, Model EGN4. Manufacturer: Oxford Applied Research, United Kingdom. Intended Use: See notice at 65 FR 26583, May 8, 2000.

*Comments:* None received. Decision: Approved. No instrument of equivalent scientific value to the foreign instrument, for such purposes as it is intended to be used, is being manufactured in the United States. Reasons: The foreign instrument provides: (1) Capability to evaporate four different materials and (2) an interface to a vacuum chamber via a 2<sup>3</sup>/<sub>4</sub> inch CF flange. Two domestic manufacturers of similar equipment advise that (1) These capabilities are pertinent to the applicant's intended purpose and (2) they know of no domestic instrument or apparatus of equivalent scientific value to the foreign instrument for the applicant's intended use.

We know of no other instrument or apparatus of equivalent scientific value to the foreign instrument which is being manufactured in the United States.

**Frank W. Creel,**

*Director, Statutory Import Programs Staff.*

[FR Doc. 00-15524 Filed 6-19-00; 8:45 am]

**BILLING CODE 3510-DS-P**

## DEPARTMENT OF COMMERCE

### National Institute of Standards and Technology

#### **Notice of Prospective Grant of Exclusive Patent License**

**AGENCY:** National Institute of Standards and Technology Commerce.

**ACTION:** Notice of Prospective Grant of Exclusive Patent License.

**SUMMARY:** This is a notice in accordance with 35 U.S.C. 209(c)(1) and 37 CFR 404.7(a)(1)(i) that the National Institute of Standards and Technology ("NIST"), U.S. Department of Commerce, is contemplating the grant of an exclusive license in the United States of America, its territories, possessions and commonwealths, to NIST's interest in the invention embodied in U.S. Patent Application 09/016,668, titled, "Temperature Calibration Wafer For Rapid Thermal Processing Using Thin-Film Thermocouples", filed January 27, 1998; NIST Docket No. 97-021US to Claud S. Gordon Co., having a place of business at 5710 Kenosha St., Richmond, IL. The grant of the license would be for the field of use of Semiconductor Manufacturing.

**FOR FURTHER INFORMATION CONTACT:** J. Terry Lynch, National Institute of Standards and Technology, Office of Technology Partnerships, Building 820, Room 213, Gaithersburg, MD 20899.

**SUPPLEMENTARY INFORMATION:** The prospective exclusive license will be royalty-bearing and will comply with the terms and conditions of 35 U.S.C. 209 and 37 CFR 404.7. The prospective exclusive license may be granted unless, within sixty days from the date of this published Notice, NIST receives written evidence and argument which establish that the grant of the license would not be consistent with the requirements of 35 U.S.C. 209 and 37 CFR 404.7. The availability of the invention for licensing was published in the **Federal Register**, Vol. 63, No. 42 (March 4, 1998).

U.S. Patent application 09/016,668 is owned by the U.S. Government, as represented by the Secretary of Commerce. The present invention enables the measurement of temperature and the calibration of temperature measurements in rapid thermal processing tools for silicon wafer processing to a greater accuracy than previously possible. The invention is a device which is a calibration wafer of novel construction and capabilities. The calibration wafer is comprised of an array of junctions of thin film thermocouples which traverse the